

**REPLY UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER 2800**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| | | | |
|------------------------------|--|--------------------|-----------------------------|
| In Re Application of: | Divakaruni et al. | Conf. No.: | 1387 |
| Serial No.: | 10/707,388 | Art Unit: | 2891 |
| Filed: | 12/10/2003 | Examiner: | Fulk, Steven J. |
| Title: | SILICIDE RESISTOR IN BEOL LAYER OF SEMICONDUCTOR DEVICE AND METHOD | Docket No.: | FIS920030274 (IBMF-0032) |

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AFTER-FINAL REQUEST FOR RECONSIDERATION

Sir:

I. INTRODUCTORY COMMENTS:

In response to the Final Office Action of December 07, 2006, please reconsider the above-referenced patent application in view of the following remarks: